Ellipsometer

- Rudolph AutoEL IV-NIR-III ellipsometer is located in the Class-1000 cleanroom and offers three wavelength for measurement: 405, 633, and 830 nm.

- Measures a wide variety of films on wafers up to 6” in diameter. Measurable films include: SiO2/Si, Si3N4/Si, resist/Si, Si3N4/SiO2/Si, Resist/SiO2/Si, Polysilicon/SiO2,Si, Thin metal film, and Organic films.